ADVANCED
FUNCTIONAL
MATERIALS

HIERARCHICAL STRUCTURES

K. P. Loh and co-workers develop a method to synthesize wafer scale, high-quality, few-layer, hexagonal boron nitride (h-BN) films. On page 731, they use a remotely discharged plasma beam source in high vacuum. Lithographic patterning of layer-by-layer stacked h-BN and graphene films enables the fabrication of a (h-BN-G)n disk array, which can exhibit tunable plasmonic resonances in the infrared region depending on the height of the disk. Plasmonic resonance upshifts of up to 240 cm^{-1} are demonstrated.

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